

Optical Microlithography XXIII: 23-25 February 2010, San Jose, California, United States

by Mircea V Dusa Willard Conley SPIE (Society)
SEMATECH (Organization)

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San Jose. 7640 Optical Microlithography XXIII (Dusa), p. 19-59 Tuesday-Thursday 23-25. Associate Professor Idriss Blakey - Australian Institute for . Years: 2018 2017 2016 2015 2014 2013 2012 2011 2010 2009 2008 2007 2006 . Microthermoforming of microfluidic substrates by soft lithography (μ TSL): 2018 International Biotech Innovation Days, 23 - 25 May 2018 / Senftenberg, 2005 January 30 – February 3, 2005, San Jose, CA, USA Proc. Connecting minds for global solutions - SPIE In his illustrious career, he was heavily involved in the IEEE Control Systems . a comparative analysis among selective-laser melting and stereo-lithography WSEAS transactions on advances in engineering education 7 (2010): 129-138 . Meeting on Internet and Audiology, Louisville (KY) USA, 27-28 July 2017 proceedings of spie - SPIE Digital Library 2009?12?15? . 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